

(51) International Patent Classification:

G01F 1/00 (2006.01)

G01F 15/06 (2006.01)

(21) International Application Number:

PCT/US2013/038732

(22) International Filing Date:

30 April 2013 (30.04.2013)

(25) Filing Language:

English

(26) Publication Language:

English

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(81) Designated States (unless otherwise indicated, for every kind of national protection available): AE, AG, AL, AM, AO, AT, AU, AZ, BA, BB, BG, BH, BN, BR, BW, BY, BZ, CA, CH, CL, CN, CO, CR, CU, CZ, DE, DK, DM, DO, DZ, EC, EE, EG, ES, FI, GB, GD, GE, GH, GM, GT,

HN, HR, HU, ID, IL, IN, IS, JP, KE, KG, KM, KN, KP, KR, KZ, LA, LC, LK, LR, LS, LT, LU, LY, MA, MD, ME, MG, MK, MN, MW, MX, MY, MZ, NA, NG, NI, NO, NZ, OM, PA, PE, PG, PH, PL, PT, QA, RO, RS, RU, RW, SC, SD, SE, SG, SK, SL, SM, ST, SV, SY, TH, TJ, TM, TN, TR, TT, TZ, UA, UG, US, UZ, VC, VN, ZA, ZM, ZW.

(84) Designated States (unless otherwise indicated, for every kind of regional protection available): ARIPO (BW, GH, GM, KE, LR, LS, MW, MZ, NA, RW, SD, SL, SZ, TZ, UG, ZM, ZW), Eurasian (AM, AZ, BY, KG, KZ, RU, TJ, TM), European (AL, AT, BE, BG, CH, CY, CZ, DE, DK, EE, ES, FI, FR, GB, GR, HR, HU, IE, IS, IT, LT, LU, LV, MC, MK, MT, NL, NO, PL, PT, RO, RS, SE, SI, SK, SM, TR), OAPI (BF, BJ, CF, CG, CI, CM, GA, GN, GQ, GW, ML, MR, NE, SN, TD, TG).

Declarations under Rule 4.17:

— as to applicant's entitlement to apply for and be granted a patent (Rule 4.17(ii))

Published:

— with international search report (Art. 21(3))

(54) Title: VOLUME FLOW SENSOR SYSTEM COMPRISING A MASS FLOWMETER AND A DENSITY METER

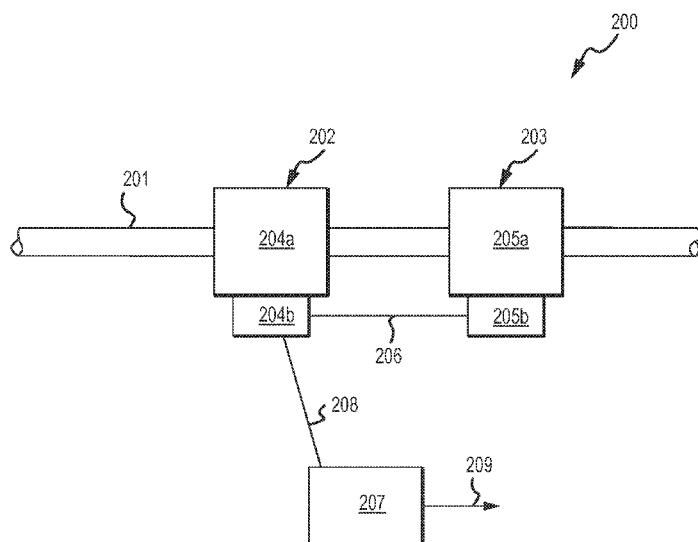


FIG. 2

(57) Abstract: A flow rate sensor system (200) is provided. The flow rate sensor system (200) includes a density or specific gravity meter (202) including a sensor assembly (204a) and a density or specific gravity meter electronics (204b) configured to generate a density or specific gravity measurement of a process fluid. The flow rate sensor system (200) further includes a mass flow meter (203) including a sensor assembly (205a) and a mass flow meter electronics (205b) configured to generate a mass flow rate of the process fluid and in electrical communication with the density or specific gravity meter electronics (204b). A remote processing system (207) is provided that is in electrical communication with only one of the density or specific gravity meter electronics (204b) or the mass flow meter electronics (205b). The remote processing system (207) is configured to receive a volume or energy flow measurement of the process fluid generated by the density or specific gravity meter electronics (204b) or the volumetric meter electronics (205b) based on the generated density or specific gravity measurement and the generated mass flow rate.